WANG YUEH AND ERNISSE S. PUTNA
REDUCING OUTGASSING OF EXPOSURE OF PHOTOLITHOGRAHY RESISTS
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Timothy N. Trop, Reg. No. 28,994, (713) 468-8880
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Applicant: Title: Docket No.: Express Mail: Atty:

FIG. 1

$$R_1$$
 R_2
 R_3
 R_4

FIG. 2